

### Inventor Information

Inventor One Given Name:: Yoshiro  
Family Name:: SHIOKAWA  
Name Suffix::  
City of Residence:: Hachioji-shi  
State or Prov. of Residence:: Tokyo  
Country of Residence:: Japan  
Citizenship Country:: Japan  
Inventor Two Given Name:: Megumi  
Family Name:: NAKAMURA  
Name Suffix::  
City of Residence:: Fuchu-shi  
State or Prov. of Residence:: Tokyo  
Country of Residence:: Japan  
Citizenship Country:: Japan  
Inventor Three Given Name:: Toshihiro  
Family Name:: FUJII  
Name Suffix::  
City of Residence:: Hamura-shi  
State or Prov. of Residence:: Tokyo  
Country of Residence:: Japan  
Citizenship Country:: Japan  
Inventor Four Given Name::  
Family Name::  
Name Suffix::  
City of Residence::  
State or Prov. of Residence::  
Country of Residence::  
Citizenship Country::  
Inventor Five Given Name ::  
Family Name::  
Name Suffix::  
City of Residence::  
State or Prov. of Residence::  
Country of Residence::  
Citizenship Country::

### Correspondence Information

Correspondence Customer Number:: 25944

### Application Information

Title Line One:: METHOD AND APPARATUS FOR ION  
Title Line Two:: ATTACHMENT MASS SPECTROMETRY  
Title Line Three::  
Title Line Four::  
Total Drawing Sheets:: 9  
Docket Number:: 111522

### Continuity Information

>This application is a:: Division of  
Application One::  
Filing Date::  
Patent Number::  
which is a:: Division of  
>>Application Two::  
Filing Date::  
Patent Number::

### **Prior Foreign Applications**

Foreign Application One:: JP 2000-401483  
Filing Date:: December 28, 2000  
Country:: Japan  
Priority Claimed:: Yes  
Foreign Application Two::  
Filing Date::  
Country::  
Priority Claimed::  
Foreign Application Three::  
Filing Date::  
Country::  
Priority Claimed::

### **Assignee Information**

Name of assignee:: ANELVA CORPORATION  
Assignee Address Line One:: 8-1, Yotsuya 5-chome,  
Assignee Address Line Two::  
City:: Fuchu-shi  
State or Province:: Tokyo  
Country:: Japan  
Postal or Zip Code::